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(71) Applicant: EDWARDS VACUUM LLC [US/US]; 6416
Inducon Drive West, Sanborn, New York 14132 (US).

(72) Inventor: CASELLO, John; Edwards Vacuum LLC, 15
Elizabeth Drive, Chelmsford, Massachusetts 01824 (US).

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(54) Title: CRYOPUMPS AND INLET FLOW RESTRICTORS FOR CRYOPUMPS

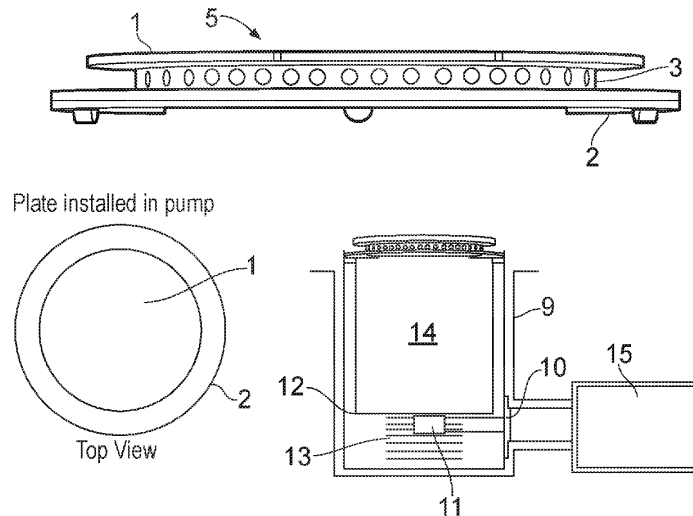


FIG. 4

(57) Abstract: A flow restrictor for restricting a flow rate of gas flowing into a cryopump and the cryopump are disclosed. The flow restrictor is configured to be mounted in an inlet of the cryopump, the flow restrictor comprising: an inlet component for providing a gas flow path into the cryopump; a shielding plate mounted to at least partially obscure the gas flow path through the inlet component; and an intermediate component linking the shielding plate to the inlet component, the intermediate component comprising at least one aperture, the at least one aperture defining at least one gas flow path into the cryopump. The shielding plate is configured to shield the gas flow path through the inlet component such that when mounted on the cryopump there is no direct line of sight path through the inlet component to a cryopanel within the cryopump.

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